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12/28/05

Date

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No.: 10/711,649
Filed: September 29, 2004
Group Art Unit: 1756
Examiner: Unknown
Applicant: Kohei Kawamura et al.
Title: **A METHOD FOR SUPERCRITICAL CARBON DIOXIDE
PROCESSING OF FLUORO-CARBON FILMS**
Attorney Docket: SSIT-114
Confirmation No.: 5648

Cincinnati, Ohio 45202

December 28, 2005

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

In accordance with the duty of candor and good faith imposed by 37 CFR §1.56 and means of complying therewith according to 37 CFR §§1.97 and 1.98, the references listed on the attached PTO-1449 are called to the attention of the United States Patent and Trademark Office in connection with the above-identified patent application. Because the requirement (37 C.F.R. §1.98(a)(2)(i)) for submitting copies of U.S. patents and published applications has been waived, copies of only the foreign cited references are enclosed herewith.

No admission is made that the cited art represents the prior art or that the cited art is the most material art.

The Examiner is urged to consider the cited references and to make an independent decision with respect to their materiality.

In accordance with 37 CFR § 1.97(b), this supplemental information disclosure statement shall be considered because it is filed before the mailing date of a first Office Action on the merits. Applicant believes no fee is due in connection with the filing of this paper. If a fee is due, please charge Deposit Account Number 23-3000.

Respectfully submitted,

WOOD, HERRON & EVANS, L.L.P.

By: 
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SUBSTITUTE FORM PTO-1449 (MODIFIED)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. SSIT-114		SERIAL NO. 10/711,649	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)				APPLICANT Kawamura et al.		FILING DATE 09/29/2004	
U.S. PATENT DOCUMENTS				GROUP 1756			
EXAMINER INITIAL		PATENT NUMBER	ISSUE DATE	PATENTEE	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	A.A	6 5 9 6 0 9 3	07/22/2003	DeYoung et al.	134	36	09/13/2001
	A.B						
	A.C						
	A.D						
	A.E						
	A.F						
	A.G						
	A.H						
	A.I						
	A.J						
	A.K						
FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS							
		DOCUMENT NUMBER	PUBLICATION DATE	COUNTRY OR PATENT OFFICE	CLASS	SUBCLASS	TRANSLATION (YES/NO)
	A.L	JP 4-284648	10/09/1992	JP	H01L	21/68	Abstract Only
	A.M	JP 62-111442	05/22/1987	JP	H01L	21/68	Abstract Only
	A.N	JP 63-256326	10/24/1988	JP	B23Q	3/08	Abstract Only
	A.O						
	A.P						
	A.Q						
OTHER DOCUMENTS (Including Author, Title, Date, Place of Publication)							
	A.R	Cotte et al., Process and Apparatus for Contacting a Precision Surface with Liquid or Supercritical Carbon Dioxide, US 2003/0196679 A1; Publication Date 10/23/2003; Filing Date 04/18/2002; U.S. Class 134/1					
	A.S						
	A.T						
EXAMINER				DATE CONSIDERED			
EXAMINER: Initial if citation considered, whether or not in conformance. Draw line through citation only if not in conformance <u>and</u> not considered. Include a copy of this form with next communication to Applicant.							